Micro device product manufacturing system
Herstellungssystem für Mikrokomponenten
Système de production de dispositif microélectronique

Designated Contracting States: DE FI FR

Priority: 15.10.1999 US 418732

Date of publication of application: 18.04.2001 Bulletin 2001/16

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Description

[0001] The present invention relates generally to a manufacturing system for electronic products, and more particularly to production of electronic circuit boards incorporating programmable integrated circuits.

[0002] In the past, certain operations of electronic circuit board assembly were performed away from the main production assembly lines. While various feeder machines and robotic handling systems would populate electronic circuit boards with integrated circuits, the operations related to processing integrated circuits, such as programming, testing, calibration, and measurement were performed in separate areas on separate equipment rather than being integrated into the main production assembly lines.

[0003] For example, in the programming of programmable devices such as electrically erasable programmable read-only memories (EEPROMs) and Flash EEPROMs, separate programming equipment was used which was often located in a separate area from the circuit board assembly lines. There were a number of reasons why programming was done off-line.

[0004] First, the programming equipment was relatively large and bulky. This was because of the need to accurately insert and remove programmable devices at high speeds into and out of programming sockets in the programmer. Since insertion and removal required relatively long traverses at high speed and very precise positioning, very rigid robotic handling equipment was required. This rigidity requirement meant that the various components had to be relatively massive with strong structural support members to maintain structural integrity and precision positioning of the pick and place systems moving at high speeds. Due to the size of the programming equipment and the limited space for the even larger assembly equipment, they were located in different areas.

[0005] Second, a single high-speed production assembly system could use up programmed devices faster than they could be programmed on a single programming mechanism. This required a number of programming systems which were generally operated for longer periods of time in order to have a reserve of programmed devices for the production assembly systems. This meant that the operating times and the input requirements were different between the two systems.

[0006] Third, no one had been able to build a single system which could be easily integrated with both the mechanical and electronic portions of the production assembly systems. These systems are complex and generally require a great deal of costly engineering time to make changes to incorporate additional equipment.

[0007] A major problem associated with programming the programmable devices in a separate area and then bringing the programmed devices into the production assembly area to be inserted into the electronic circuit boards was that it was difficult to have two separate processes running in different areas and to coordinate between the two separate systems. Often, the production assembly line would run out of programmable devices and the entire production assembly line would have to be shut down. At other times, the programming equipment would be used to program a sufficient inventory of programmed devices to assure that the production assembly line would not be shut down; however, this increased inventory costs. Further problems were created when the programming had to be changed and there was a large inventory of programmed integrated circuits on hand. In this situation, the inventory of programmable devices would have to be reprogrammed with an accompanying waste of time and money.

[0008] While it was apparent that a better system would be desirable, there appeared to be no way of truly improving the situation. There were a number of apparently insurmountable problems that stood in the way of improvement.

[0009] First, the operating speeds of current production assembly lines so greatly exceeded the programming speed capability of conventional programmers that the programmer would have to have a much greater throughput than thought to be possible with conventional systems.

[0010] Second, not only must the programmer be faster than existing programmers, it would also have to be much smaller. The ideal system would integrate into a production assembly line, but would do so without disturbing an existing production assembly line or requiring the lengthening of a new production assembly line over that of the length without the ideal system. Further, most of these production assembly lines were already filled with, or designed to be filled with, various types of feeding and handling modules which provide limited room for any additional equipment.

[0011] Third, any programmer integrated with the production assembly line would apparently also have to interface with the control software and electronics of the production system software for communication and scheduling purposes. This would be a problem because production assembly line system software was not only complex, but also confidential and/or proprietary to the manufacturers of those systems. This meant that the integration must be done with the cooperation of the manufacturers, who were reluctant to spend engineering effort on anything but improving their own systems, or must be done with a lot of engineering effort expended on understanding the manufacturers' software before working on the programmer's control software.

[0012] Fourth, the mechanical interface between a programmer and the production equipment needed to be highly accurate for placing programmed devices relative to the pick-and-place handling equipment of the production assembly system.

[0013] Fifth, there are a large number of different manufacturers of production handling equipment as well as production manufacturing equipment. This means that a
large number of different production assembly line configurations would have to be studied and major compromises in design required for different manufacturers.

[0014] Sixth, the ideal system would allow for changing quickly between different micro devices having different configurations and sizes.

[0015] Seventh, the ideal system needed to be able to accommodate a number of different micro device feeding mechanisms including tape, tube, and tray feeders.

[0016] Finally, there was a need to be able to quickly reject micro devices which failed during the programming.

[0017] All the above problems seemed to render an effective solution impossible. This was especially true when trying to invent a comprehensive system which would be portable, allow "plug and play" operation with only external electric and air power, provide automated programming and handling, and be able to present programmed programmable devices to an automated production assembly line.

[0018] EP-A-0 517 439 discloses a component manufacturing system that uses a robotic structure to electrically configure and program each selected and aligned component in real time and to install each component at a predefined circuit board location.

[0019] The present invention provides a micro device product manufacturing system which includes a production assembly line with a feeder/processing/buffer system. The feeder/processing/buffer system has a flexible feeder mechanism for receiving micro devices in a number of different manners, a processing mechanism for performing a processing operation on the micro devices at a high rate of speed, and an output buffer mechanism for providing the processed micro devices to the production assembly line on a continuous basis. The system substantially solves all the problems which previously faced such systems.

[0020] The present invention further provides a feeder/processing/buffer system which has a flexible feeder mechanism for receiving a plurality of micro devices, a processing mechanism for performing a processing operation on the micro devices, and an output buffer mechanism for providing the processed micro devices to a production assembly line. The system substantially solves all the problems which previously faced such systems.

[0021] The present invention further provides a feeder/processing/buffer system in which an input feeder mechanism for receiving micro devices, a processing mechanism for performing a processing operation on the micro devices, and an output buffer mechanism for providing the processed micro devices to a production assembly line are aligned with each other and have primarily one degree of freedom to increase speed and productivity. The system substantially solves all the problems which previously faced such systems.

[0022] The present invention further provides a feeder/processing/buffer system in which a reduced number of components comprising an input feeder mechanism for
[0028] A preferred embodiment of the invention for achieving the above objective and advantageous embodiments and features thereof are given in the appended independent claim and the sub claims.

[0029] The above and additional advantages of the present invention will become apparent to those skilled in the art from a reading of the following detailed description when taken in conjunction with the accompanying drawings.

FIG. 1 (PRIOR ART) is an example of a prior art programming system;

FIG. 2 (PRIOR ART) is an example of an electronic circuit board manufacturing line of the prior art which is part of the present invention;

FIG. 3 is a side view of the feeder/programmer/buffer system of the present invention;

FIG. 4 is a top view of FIG. 3 taken along line 4--4;

FIG. 5 is a side view of an alternative embodiment of the present invention; and

FIG. 6 is a further alternate embodiment of the present invention.

[0030] Referring now to FIG. 1 (PRIOR ART), therein is shown a conventional processing system, such as a programming system 10 for programmable electronic devices. The programming system 10 is used as an example. The programming system 10 is extremely large and has a rigid frame 12 to which an input feeder 14 is attached. The input feeder 14 can be a tray, tray stacker, tube, tube stacker, or tape and reel, which supplies unprogrammed devices to the programming system 10.

[0031] A robotics handling system 18, which is capable of moving in an X-Y-Z and Ï€ coordinate system (with X and Y being horizontal movements, Z being vertical, and Ï€ being angular), carries a pick-and-place (PNP) head 20 for picking up the unprogrammed devices and moving them into a programming area 22 and inserting them into programming sockets (not shown) in the programming system 10.

[0032] When the programming is complete, the robotics handling system 18 will move the PNP head 20 into place to remove the parts from the programming sockets and place them into an output mechanism 24. If the programmable devices could not be programmed, the robotics handling system 18 and the PNP head 20 will deposit the defective device into a reject bin 26.

[0033] The programming system 10 will continue to operate automatically until all the good devices in the input mechanism 14 are programmed and transferred to the output mechanism 24.

[0034] Referring now to FIG. 2 (PRIOR ART), therein is shown a production assembly system 30 which includes an assembly line 31. The production assembly system 30 includes a feeder table 32 where various input feeders, such as the input feeders 34, are attached. Where programmed devices are involved, the output mechanism 24 from FIG. 1 (PRIOR ART) would be used as the input feeder 34. In FIG. 2 (PRIOR ART), two feeders 34 and 36 are shown installed, where each of the input feeders 34 and 36 could contain different types of programmable devices. The input feeders 34 and 36 can be trays, tray stackers, tubes, tube stackers, or tapes and reels.

[0035] The production assembly system 30 has a support frame 37 which carries a robotics handling system 40, which is capable of carrying a PNP head 42 along an X-Y-Z-Ï€ coordinate system to take devices from the input feeders 34 and 36 and place them on printed circuit boards 38 as they are moved along a conveyor belt 48 which is mounted in assembly line frame 46. The input feeders 34 and 36 are located offset from the direction of movement of the conveyor belt 48.

[0036] Referring now to FIG. 3, therein is shown one embodiment of a portion of the present invention, a feeder/programmer/buffer system 50, which is an in-line, linear operation system and which fits in the same place in the production assembly system 30 as one of the input feeders 34 or 36. The ability to fit the input feeder/programmer/buffer system 50 into roughly the same space and location as a feeder provides a new production assembly system which is capable of simplified, sustained high-speed processing and assembly operation.

[0037] A number of different input mechanisms may be used to feed the input feeder/programmer/buffer system 50 including a tube, tube stacker, tray, tray stacker, or a tape and reel as used with prior art systems. Due to the in-line configuration, the feeder/programmer/buffer system 50 is able to flexibly accommodate different feeding options with minimal changes. In the best mode, the feeder/programmer/buffer system 50 has an input mechanism which is a tape and reel feeder. The reel could be placed in a number of different positions such as underneath the feeder/programmer/buffer system 50 as indicated by an input reel 52, in front as indicated by an input reel 54, or be entirely separated from the feeder/programmer/buffer system 50 (not shown). Where the input reel 52 or 54 is part of the feeder/programmer/buffer system 50, it is supported by a frame 56 to allow rotation of the input reels 52 or 54 in a clockwise direction as shown in FIG. 3 by a drive mechanism (not shown) which could be a motor or a belt from another motor as will later be described.

[0038] Using input reel 54 as an example of an input feeder mechanism 55, unprogrammed devices are input between a carrier tape 58 and a cover tape 60. The carrier tape 58 has a plurality of small pockets for holding unprogrammed devices, or incorrectly programmed devices if reprogramming needs to be performed.

[0039] In the first stage, the cover tape 60 will be peeled off and fed to a cover tape mechanism 62, which handles disposal of the cover tape 60 by rolling it on to a spool or crushing it for later removal and disposal. The cover tape mechanism 62 applies tension to the cover tape 60 to assure that it is peeled off of the carrier tape 58. The peeling off of the cover tape 60 exposes the unpro-
programmed devices on the carrier tape 58.

[0040] An indexer or tape-in mechanism 64, which is part of the input feeder mechanism 55, includes a motor driven sprocket (not shown), which may include the previously described belt to rotate the input reel 52 or 54, to help pull the carrier tape 58 off the input reel 52 or 54 and bring the unprogrammed devices to a handling mechanism 65 which includes a PNP head 66 in a robotics handling system 69.

[0041] To have an elegantly simple system, the feeder/programmer/buffer system 50 is a linear operation system, and the robotics handling system 69 needs to only provide X-axis movement back and forth along the inline length. The PNP head 66 contains one or more individual pickup mechanisms or probes 67 which provide vertical Z-axis movement for picking up the programmable devices. This in-line linear approach greatly simplifies overall operation of the feeder/programmer/buffer system 50 and reduces the overall size so that the feeder/programmer/buffer 50 can fit the desired minimum space profile.

[0042] To optimize throughput, the PNP head 66 has a plurality of probes 67 to pick up a plurality of unprogrammed devices sequentially. The number of unprogrammed devices picked up at one time will be a function of the speed of the feeder/programmer/buffer system 50. The more unprogrammed devices programmed in a single operation, the greater the throughput, but the larger the feeder/programmer/buffer system 50. Multiple unprogrammed devices could be picked up simultaneously if the center-to-center spacing of the micro devices as input did not change, but in the preferred embodiment, four unprogrammed devices are picked up sequentially.

[0043] The PNP head 66 could also incorporate a marking device 68, such as a stamp or ink pen, for marking the devices to indicate production lots or feeder/programmer/buffer used. As would be evident, the placement of the marking device is a matter of design.

[0044] Referring briefly to FIG. 4, therein is shown a top view of FIG. 3 along line 4 - 4. All the same elements as in FIG. 3 are designated by the same nomenclature and numbers as in FIG. 3. Of particular interest in FIG. 4, is a programming mechanism 70 showing four programmer socket locations 70A through 70D and the pick-up area 80 at the far end of the feeder conveyor belt 74.

[0045] Referring now back to FIG. 3, therein is shown a side view of the programming mechanism 70. After the plurality of unprogrammed devices are picked up, they are moved by the robotics handling system 69 over to the programming mechanism 70 which has a plurality of sockets 70A through 70D into which the unprogrammed devices are sequentially placed by insertion or dropping by the probes 67 of the PNP head 66. Again, if the center-to-center spacing of the micro devices did not change, a simultaneous placement could be performed.

[0046] The unprogrammed devices are then programmed by the programming mechanism 70. The simultaneous programming can be accomplished just by connecting the plurality of sockets in parallel. The sequential programming can be accomplished by connecting the plurality of sockets separately or on a series bus. This multiplies the throughput of the present invention by a factor equal to the plurality of programmable devices being programmed over the prior art programming mechanisms. One additional feature in the programming mechanism 70 is the capability of identifying when a device cannot be programmed because it has failed processing or is "bad".

[0047] After the programming, the programmed devices may be extracted from the sockets by a number of different methods, but in the best mode, the PNP head 66 of the handling system 65 will perform sequential pick-up. Again, if the center-to-center spacing of the micro devices did not change, a simultaneous extraction could be performed.

[0048] The PNP head 66 moves the bad programmable devices and deposits them in a reject bin 72 and deposits the good programmed devices into an output buffer mechanism 75 which includes a buffer conveyor belt 76 which is on rollers 77 and 78. The buffer conveyor belt 76 is equipped with features for holding the programmable devices in place such as groves, pockets, or other holders, represented by pockets 79 (only one shown).

[0049] The buffer conveyor belt 76 moves the programmable devices to the pickup area 80 from where the robotic handling system which is part of the production assembly system 30, indicated by the phantom line in FIG. 3 and shown in FIG. 2 (PRIOR ART), will pick them up for population of the printed circuit boards. The buffer conveyor belt 76 can be speeded up or slowed down to accommodate the rate at which the programmed devices are required by the production assembly system and thus provide a reserve, or buffer, of programmed devices. The output buffer mechanism 75 may operate at different speeds from the remainder of the system because it is effectively uncoupled from the rest of the system and can provide programmed devices on demand. This creates a novel, new combination of a programmed product manufacturing system which includes the feeder/programmer/buffer system 50 and the production assembly system 30.

[0050] It should be noted that the programming could be performed such that the robotics handling system 69 and the PNP head 66 are in continuous operation picking and placing devices while other unprogrammed devices are being programmed by the programming mechanism 70. In the best mode, the PNP head 66 traverses to the pickup area of the tape-in mechanism 64, picks up four sequential programmable devices, sequentially places them into the sockets 70A through 70D in the programming mechanism 70, and waits until the programming is done. Then it picks up the programmable devices from the sockets 70 A through 70D and places the bad parts in the reject bin 72 and the good parts on the buffer conveyor belt 76 which moves sufficiently to allow sequential placement of the programmed devices. The PNP head
66 then traverses back to the tape-in mechanism 64 to pickup four new programmable devices.

[0051] The carrier tape 58 is discarded through the feeder/programmer/buffer system 50. It should be understood that the carrier tape 58 moves at a different rate from the buffer conveyor belt 76 because the two parts are not coupled. The reason for this, in addition to the buffer function, is that there are periodic rejected programmable devices, which means that the input feed must be faster than the output feed.

[0052] Referring now to FIG. 5, therein is shown an alternate embodiment of a portion of the present invention, a feeder/programmer/buffer system 100 which is an in-line, rotary operation system and which fits in the same place in the production assembly system 30 of FIG. 2 as one of the input feeders 34 or 36. The ability to fit the feeder/programmer/buffer system 100 into the same space and location as a feeder provides a new production assembly system which is capable of simplified, sustained high-speed processing and assembly operation.

[0053] Just as for the feeder/programmer/buffer system 50, a number of different input mechanisms may be used to feed the feeder/programmer/buffer system 100 including a tube, tube stacker, tray, tray stacker, or a tape and reel. Due to the in-line configuration, the feeder/programmer/buffer system 100 is able to flexibly accommodate different feeding options with minimal changes. In the best mode, the feeder/programmer/buffer system 100 has an input feeder mechanism which is a tape feeder. The feeder/programmer/buffer system 100 shows two positions for input reels 102 and 104 in FIG. 5.

[0054] Using the input reel 104 as an example of an input feeder mechanism 105, a carrier tape 108 carrying the unprogrammed devices has a cover tape 110 which is peeled off and stored for disposal in a cover tape mechanism 112. The unprogrammed devices are moved by the carrier tape 108 into a tape-in mechanism 114 which is part of an input feeder mechanism 105 where a pick and place (PNP) rotor 116 picks the individual programmable devices up using pick and place (PNP) heads 116A through 116F. It would be understood that the number PNP heads is merely a matter of design for the feeder/programmer/buffer system 100. The PNP rotor 116 could also be designed to make X and/or Z traverses to improve pickup and placement.

[0055] The pickup rotor 116 rotates in a counter-clockwise direction position where the PNP heads 116A through 116F can place the unprogrammed devices on a programmer rotor 118 which has a plurality of programmer heads 118A through 118F which correspond to the pickup rotor PNP heads 116A through 116F, although this again is merely a matter of design and the number of programmer heads and pickup rotor heads could be different.

[0056] The programmer rotor 118 rotates in a clockwise direction and programs the devices while rotating. When programming is complete, the programmed devices are removed by a place rotor 120 having PNP heads 120A through 120F which correspond with the programmer rotor PNP heads 118A through 118F, again with the number of heads being merely a matter of design. The programmer rotor 118 could also be designed to make X and/or Z traverses to improve pickup and placement.

[0057] The place rotor 120 picks the programmable devices from the programmer rotor heads 118A through 118F and, while rotating in a counter-clockwise direction, deposits the good programmed devices onto an output buffer mechanism 121. It would be understood that the place rotor 120 could be designed to make X and/or Z traverses to improve pickup and could also perform as an output buffer mechanism 121 itself by picking up programmed devices and shuttling back and forth in the X direction between the programmer rotor 118 and the handling system pick point.

[0058] Thus, the pickup rotor 116 and the place rotor 120 could be considered part of a handling mechanism 119 for the feeder/programmer/buffer system 100. The pickup rotor 116, the programmer rotor 118, and the place rotor 120 could also be considered part of a programming mechanism 115 or a combined programming and output buffer system.

[0059] In the best mode, however, the place rotor 120 properly positions the programmed devices in the output buffer mechanism 121 into the correct orientation for the robotic handling system 40 which is part of the production assembly system 30 to pick them up for population of the printed circuit boards 38 of FIG. 2 (PRIOR ART). The place rotor 120 places the programmed devices on to a sideways output buffer conveyor 122 which is on rollers 124 and 126 on vertical axes in the output buffer mechanism 121. The output buffer conveyor 122 could have groves, pockets, or other holders on its edge which are exemplified by vacuum holders 123 (only one shown) which use a light vacuum to hold the programmed devices in place until they are picked up by the robotics handling system 40 at the pick point.

[0060] From the above it will be understood that the present invention is applicable to what can be described as "micro devices". Micro devices include a broad range of electronic and mechanical devices. The best mode describes processing which is programming for programmable devices, which include but are not limited to devices such as Flash memories (Flash), electrically erasable programmable read only memories (E²PROM), programmable logic devices (PLDs), field programmable gate arrays (FPGAs), and microcontrollers. However, the present invention encompasses processing for all electronic, mechanical, hybrid, and other devices which require testing, measurement of device characteristics, calibration, and other processing operations. For example, these types of micro devices would include but not be limited to devices such as microprocessors, integrated circuits (ICs), application specific integrated circuits (ASICs), micro mechanical machines, micro-electro-mechanical (MEMs) devices, micro modules, and fluidic systems.
Claims

1. A micro device product manufacturing system comprising:
   a production assembly line (30) capable of providing a product ready for incorporation of a processed micro device;
   an input feeder mechanism (55) capable of providing an unprocessed micro device;
   a processing mechanism (70) capable of receiving unprocessed micro device from the input feeder mechanism (55) and processing the micro device to produce a processed micro device;
   an output buffer mechanism (75) effectively uncoupled from the rest of the system, capable of receiving the processed micro device from the processing mechanism (70) and providing the processed micro device as required to the production assembly line (30); and
   a handling system (18) capable of taking the processed micro device from the output buffer mechanism (75) and incorporating the processed micro device into the product.

2. The system as claimed in claim 1 wherein the production assembly line (30) moves in a first direction; and the input feeder, processing, and output buffer mechanisms (55, 70, 75) are in line and the input feeder, processing, and output buffer mechanisms (55, 70, 75) are at right angles to the first direction.

3. The system as claimed in claim 1 wherein the input feeder mechanism (55) is capable of providing an unprocessed micro device in a feeder selected from a group consisting of a tray, tray stacker, tube, tube stacker, and tape and reel.

4. The system as claimed in claim 1 wherein the processing mechanism (70) processes the micro device with a process selected from a group consisting of programming, calibration, test, and measurement.

5. The system as claimed in claim 1 wherein the processing mechanism (70) simultaneously processes a plurality of micro devices.

6. The system as claimed in claim 1 wherein the processing mechanism (70) includes a mechanism for detecting and rejecting failed micro devices after processing.

7. The system as claimed in claim 1 including a further handling mechanism (65) for moving micro devices among the input feeder, processing, and output buffer mechanisms (55, 70, 75) in a linear direction.

8. The system as claimed in claim 1 wherein the input feeder, processing, and output buffer mechanisms (55, 70, 75) are in line; and including a further handling mechanism (65) for moving micro devices among the input feeder, processing, and output buffer mechanisms in line using rotary movements.

9. The system as claimed in claim 1 wherein the output buffer mechanism (75) is capable of operating substantially independently from the input feeder mechanism (55) and the processing mechanism (70).

10. The system as claimed in claim 1 wherein the input feeder, processing, and output buffer mechanisms (55, 70, 75) are in line.

Patentansprüche

1. Herstellungssystem für Mikrokomponenten umfassend:
   eine Produktions-Montagebahn (30), die in der Lage ist, ein Produkt zu liefern, das zum Einbau einer verarbeitete Mikrokomponente bereit ist; einen Eingangs-Zufuhrmechanismus (55), der in der Lage ist, unverarbeitete Mikrokomponenten zu liefern; einen Verarbeitungsmechanismus (70), der in der Lage ist, die unverarbeiteten Mikrokomponenten von dem Eingabe-Fördermechanismus (55) zu empfangen und die Mikrokomponente zu verarbeiten, um eine verarbeitete Mikrokomponente zu erzeugen; einen Ausgang-Speicher-Mechanismus (75), der von dem Rest des Systems wirksam entkoppelt und in der Lage ist, die verarbeiteten Mikrokomponenten von dem Verarbeitungsmechanismus (70) zu empfangen und die verarbeiteten Mikrokomponenten nach Bedarf an die Produktions-Montagebahn (30) zu liefern; ein Handhabungssystem (18), das in der Lage ist, die verarbeiteten Mikrokomponenten von dem Ausgangs-Speicher-Mechanismus (75) abzunehmen und die verarbeiteten Mikrokomponenten in das Produkt einzubauen.


3. System nach Anspruch 1, worin der Eingangs-Fördermechanismus (55) in der Lage ist, eine unverarbeitete Mikrokomponente in einer Zufuhrvorrichtung
bereitzustellen, die ausgewählt ist aus einer Gruppe bestehend aus einem Tablet, einem Tablettsampler, einem Rohr, einem Rohrstapler und einem Band und einer Spule.

4. System nach Anspruch 1, worin der Verarbeitungsmechanismus (70) die Mikrokomponenten durch einen Prozess verarbeitet, der ausgewählt ist aus einer Gruppe bestehend aus Programmierung, Kalibrierung, Test und Messung.

5. System nach Anspruch 1, worin der Verarbeitungsmechanismus (70) gleichzeitig eine Vielzahl von Mikrokomponenten verarbeitet.

6. System nach Anspruch 1, worin der Verarbeitungsmechanismus (70) einen Mechanismus zum Detektieren und Auswerfen fehlerhafter Mikrokomponenten nach der Verarbeitung umfasst.

7. System nach Anspruch 1, umfassend einen weiteren Handhabungsmechanismus (65), um Mikrokomponenten entlang einem Eingangs-Zufuhr-, Verarbeitungs- und Ausgangs-Speicher-Mechanismus (55, 70, 75) in einer linearen Richtung zu bewegen.


Revendications

1. Système de production de dispositif microélectronique, comprenant:
   - une ligne d’assemblage de production (30) capable de fournir un produit prêt pour incorporation d’un dispositif microélectronique traité;
   - un mécanisme d’alimentation d’entrée (55) capable de fournir un dispositif microélectronique non traité;
   - un mécanisme de traitement (70) capable de recevoir le dispositif microélectronique non traité à partir du mécanisme d’alimentation d’entrée (55) et traitant le dispositif microélectronique pour produire un dispositif microélectronique traité;
   - un mécanisme tampon de sortie (75) effectivement non-couplé du reste du système capable de recevoir le dispositif microélectronique traité à partir d’un mécanisme de traitement (70) et fournissant le dispositif microélectronique traité comme exigé à la ligne d’assemblage de production (30); et
   - un système de maniement (18) capable de prendre le dispositif microélectronique traité du mécanisme tampon de sortie (75) et incorporant le dispositif microélectronique traité dans le produit.

2. Système selon la revendication 1, où la ligne d’assemblage de production (30) se meut dans une première direction; et les mécanismes, d’alimentation d’entrée, de traitement, et tampon de sortie (55, 70, 75) sont en ligne et les mécanismes, d’alimentation d’entrée, de traitement, et tampon de sortie (55, 70, 75) sont aux angles droits à la première direction.

3. Système selon la revendication 1, où le mécanisme d’alimentation d’entrée (55) est capable de fournir un dispositif microélectronique non traité dans un alimentateur choisi d’un groupe consistant en panier, empileuse de paniers, tube, empileuse de tubes, et bande et bobine.

4. Système selon la revendication 1, où le mécanisme de traitement (70) traite le dispositif microélectronique avec un procés choisi d’un groupe consistant en programmation, calibrage, test, et mesureage.

5. Système selon la revendication 1, où le mécanisme de traitement (70) traite simultanément une pluralité de dispositifs microélectroniques.

6. Système selon la revendication 1, où le mécanisme de traitement (70) comprend un mécanisme pour détecter et rejeter les dispositifs microélectroniques non correspondants après traitement.

7. Système selon la revendication 1, incluant un autre mécanisme de maniement (65) pour mouvoir les dispositifs microélectroniques entre les mécanismes, d’alimentation d’entrée, de traitement, et tampon de sortie (55, 70, 75) dans une direction linéaire.

8. Système selon la revendication 1, où les mécanismes, d’alimentation d’entrée, de traitement, et tampon de sortie (55, 70, 75) sont en ligne; et incluant un autre mécanisme de maniement (65) pour mouvoir les dispositifs microélectroniques entre les mé-
canismes, d’alimentation d’entrée, de traitement, et 
tampon de sortie en ligne en utilisant les mouve-
ments de rotation.

9. Système selon la revendication 1, où le mécanisme 
tampon de sortie (75) est capable de fonctionnement 
de manière substantiellement indépendant du mé-
canisme d’alimentation d’entrée (55) et le mécanis-
me de traitement (70).

10. Système selon la revendication 1, où les mécanis-
mes, d’alimentation d’entrée, de traitement, et tam-
pon de sortie (55, 70, 75) sont en ligne.